

Special Issue

Recent Advances in Thin Film Transistors

Message from the Guest Editor

The thin film transistor is a hot research topic in the field of displays. It has very important research significance and extensive market application prospects. At present, the key technical problems are mainly that the mobility is not high enough, the reliability is not good enough, the preparation temperature is not low enough, and the manufacturing cost is not low enough. These technical problems have seriously hindered the extensive use of the industry. At present, it is necessary to develop new thin film transistor technology and improve the performance of thin film transistors for the application of thin film transistors in new displays. Original research papers and review articles are invited for this Special Issue.

Guest Editor

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Deadline for manuscript submissions

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